

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Satoru Okamoto                      Art Unit : 1765  
Serial No. : 10/689,617                      Examiner : Mahmoud Dahimene  
Filed : October 22, 2003                      Conf. No. : 4799  
Title : METHOD FOR CLEANING PLASMA ETCHING APPARATUS, METHOD  
FOR PLASMA ETCHING, AND METHOD FOR MANUFACTURING  
SEMICONDUCTOR DEVICE

## MAIL STOP AF

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

## INFORMATION DISCLOSURE STATEMENT

Applicant requests consideration of the references listed on the attached PTO-1449 form. Under 37 C.F.R. § 1.98 (a)(2)(ii), only copies of foreign patent documents and/or non-patent literature are enclosed. Copies of any listed U.S. patents or U.S. patent application publications can be provided upon request.

Submitted herewith is an English translation of the following foreign language references, or portions thereof:

| Desig. ID | Source                                                                                   |
|-----------|------------------------------------------------------------------------------------------|
| AL        | Japan 04-313223 – English Abstract: <a href="mailto:esp@cenet.com">esp@cenet.com</a> .   |
| AM        | Japan 03-062520 – English Abstract: <a href="mailto:esp@cenet.com">esp@cenet.com</a> .   |
| AN        | Japan 2001-257197 – English Abstract: <a href="mailto:esp@cenet.com">esp@cenet.com</a> . |
| AO        | Japan 2002-043329 – English Abstract: <a href="mailto:esp@cenet.com">esp@cenet.com</a> . |

This statement is being filed after a final Office action or a Notice of Allowance, but before payment of the issue fee. Each item of information in this statement was first cited in a communication from a foreign patent office in a counterpart foreign application, the communication being dated August 21, 2007, which is not more than three months prior to the filing of this statement.

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Attorney's Docket No.: 12732-170001 / US6682

The fee in the amount of \$180 in payment of the late submission fee of §1.17(p) is being paid concurrently herewith on the Electronic Filing System (EFS) by way of Deposit Account authorization. Please apply any other charges or credits to Deposit Account No. 06-1050.

Respectfully submitted,

Date: November 20, 2007

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